

**AMENDMENTS TO THE CLAIMS:**

1. *(Currently Amended)* A polishing apparatus for polishing a workpiece, said polishing apparatus comprising:  
a polishing table having a polishing surface;  
a top ring for holding a workpiece and pressing the workpiece against said polishing surface;  
a dresser for dressing said polishing surface; and  
a sensor for observing a property irregularity or undulation of said polishing surface on said polishing table while said polishing surface is being dressed by said dresser, said sensor being mounted on said dresser.

2. *(Currently Amended)* The polishing apparatus according to claim + 5, wherein said sensor is for observing irregularity or undulation of said polishing surface.

3. *(Currently Amended)* The polishing apparatus according to claim + 5, further comprising a display device for displaying the property of said polishing surface observed by said sensor.

4. *(Currently Amended)* The polishing apparatus according to claim + 5, wherein said sensor is vertically movable independently of said top ring or said dresser.

5. *(Currently Amended)* The polishing apparatus according to claim + A polishing apparatus for polishing a workpiece, said polishing apparatus comprising:  
a polishing table having a polishing surface;  
a top ring for holding a workpiece and pressing the workpiece against said polishing surface;  
a dresser for dressing said polishing surface; and  
a sensor for observing a property of said polishing surface on said polishing table while said polishing surface is being dressed by said dresser, said sensor being mounted on said dresser,  
wherein said sensor is to observe a property of said polishing surface over an area that is larger than an area which is to be dressed by said dresser.

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6. (*Currently Amended*) A polishing apparatus for polishing a workpiece, said polishing apparatus comprising:

a polishing table having a polishing surface;  
a top ring for holding a workpiece and pressing the workpiece against said polishing surface;  
a dresser for dressing said polishing surface;  
a sensor for observing a property of said polishing surface on said polishing table while said polishing surface is being dressed by said dresser; and

a determination device for comparing an initial property of said polishing surface which is observed by said sensor with a subsequent property of said polishing surface which is subsequently observed by said sensor after said polishing surface is dressed by said dresser, and determining when to replace a component of said polishing surface based on a result of the comparison between the initial property and the subsequent property of the polishing surface which is observed after said polishing surface is dressed.

**Claim 7 (Cancelled)**

8. (*Previously Added*) The polishing apparatus according to claim 6, wherein said sensor is for observing irregularity or undulation of said polishing surface.

9. (*Previously Added*) The polishing apparatus according to claim 6, further comprising a display device for displaying the property of said polishing surface observed by said sensor.

10. (*Previously Added*) The polishing apparatus according to claim 6, wherein said sensor is vertically movable independently of said top ring or said dresser.

11. (*Previously Added*) The polishing apparatus according to claim 6, wherein said sensor is to observe a property of said polishing surface over an area that is larger than an area which is to be dressed by said dresser.

*B2*  
*Cancelled*

12. (*Previously Added*) The polishing apparatus according to claim 2, further comprising a display device for displaying the property of said polishing surface observed by said sensor.

13. (*Previously Added*) The polishing apparatus according to claim 12, wherein said sensor is vertically movable independently of said top ring or said dresser.

**Claims 14-15 (*Cancelled*)**

16. (*Previously Added*) The polishing apparatus according to claim 2, wherein said sensor is vertically movable independently of said top ring or said dresser.

**Claims 17-18 (*Cancelled*)**

19. (*Previously Added*) The polishing apparatus according to claim 3, wherein said sensor is vertically movable independently of said top ring or said dresser.

**Claims 20-22 (*Cancelled*)**

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23. (*New*) The polishing apparatus according to claim 1, further comprising a display device for displaying the property of said polishing surface observed by said sensor.

24. (*New*) The polishing apparatus according to claim 23, wherein said sensor is vertically movable independently of said top ring or said dresser.

25. (*New*) The polishing apparatus according to claim 1, wherein said sensor is vertically movable independently of said top ring or said dresser.

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